Applicant(s): Kiyoshi Mita
METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

FIG.1A

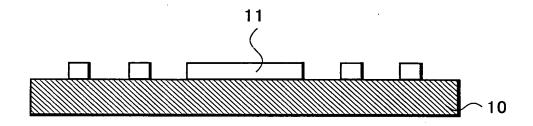
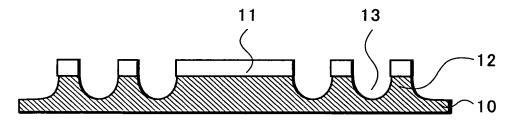


FIG.1B



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FIG.2

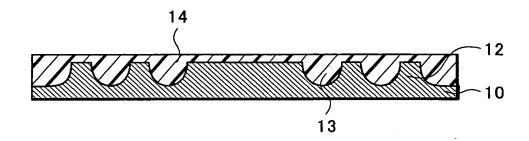


FIG.3

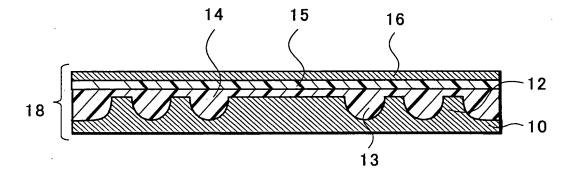
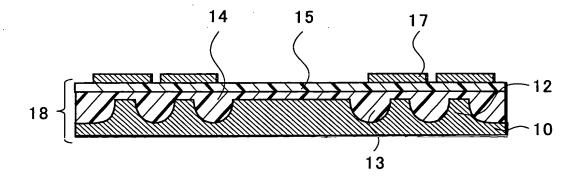


FIG.4



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FIG.5

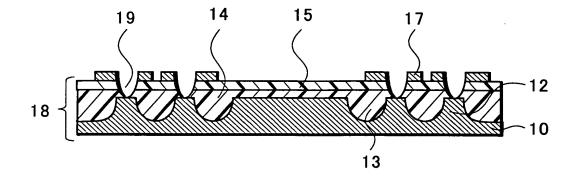


FIG.6

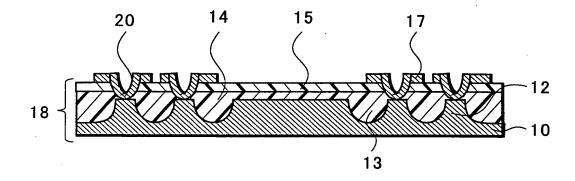
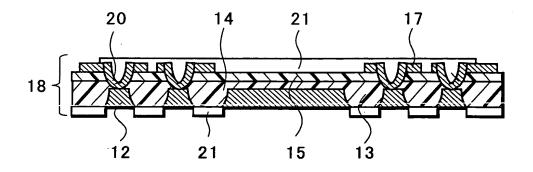


FIG.7



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FIG.8

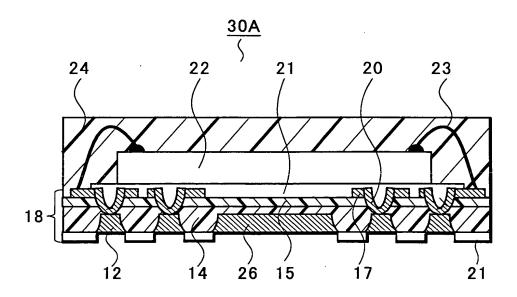
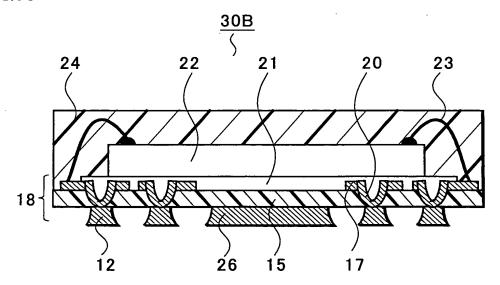


FIG.9



Applicant(s): Kiyoshi Mita
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FIG.10

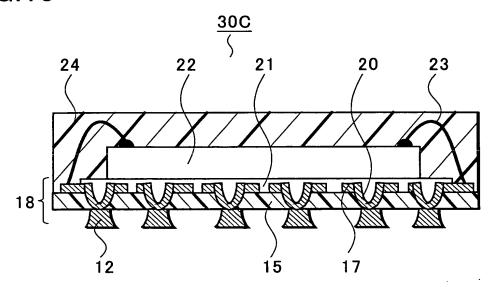
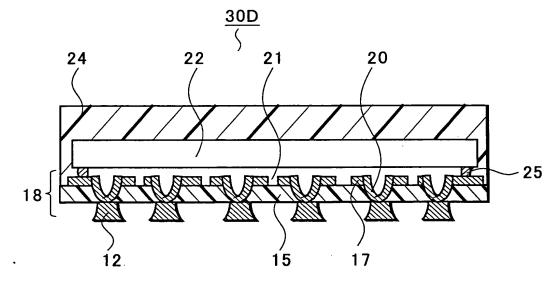


FIG.11



METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

FIG.12A

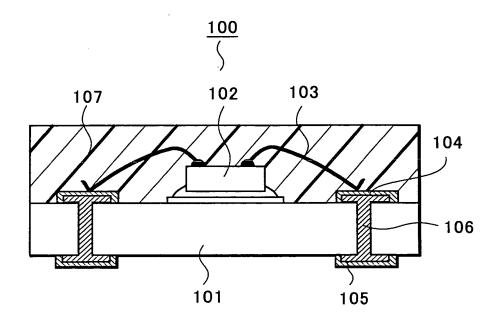


FIG.12B

